



08-06-01

Atty. Docket No. AMAT/4375/DD/BCVD/ A

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Box Patent Application
Assistant Commissioner of Patents and Trademarks
Washington, D.C. 20231

Re: Inventor(s): IAN LATCHFORD; CHRISTOPHER DENNIS BENCHER; YUXIANG WANG and MARIO DAVE SILVETTI
Title: PHOTOLITHOGRAPHY SCHEME USING A SILICON CONTAINING RESIST

Transmitted herewith is the patent application identified above, including:

Specification, claims and abstract, totaling 32 pages.
 Drawings totaling 12 pages, Formal Informal.
 Executed Declaration and Power of Attorney.
 Information Disclosure Statement w/ Form 1449 and References.
 Assignment of the invention to **Applied Materials, Inc.**
 Assignment Recordation Cover Sheet

jc971 U.S. PTO
09/921938
08/02/01

FEE CALCULATION					
Fee Items	Claims Filed	Included With Basic Fee	Extra Claims	Fee Rate	Total
Total Claims	44	-20=	24	x \$18.00	\$432.00
Independent Claims	3	-3=	0	x \$80.00	0
Basic Filing Fee				\$710.00	\$710.00
TOTAL FEES					\$1142.00

The Commissioner is hereby authorized to charge \$1142.00 to Deposit Account No. 50-1074/4375/DD/BCVD/
 The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 50-1074/4375/DD/BCVD/. A duplicate copy of this transmittal is enclosed.

Please address all future correspondence to:

PATENT COUNSEL
APPLIED MATERIALS, INC.
Legal Affairs Department
P.O.BOX 450A
Santa Clara, CA. 95052

I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to: Commissioner of Patents and Trademarks, Washington, D.C. 20231

Express Mail Receipt No EL849164681US

Date of Deposit 8-2-01

Signature Robert W. Mulcahy

Respectfully submitted,

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